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(54) **VERTICAL CAVITY SURFACE EMITTING LASER AND ATOMIC OSCILLATOR**

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H01S 5/32 (2006.01)

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ABSTRACT

A vertical cavity surface emitting laser includes: a substrate; a first mirror layer which is provided over the substrate; an active layer which is provided over the first mirror layer; a second mirror layer which is provided over the active layer; a first electrode and a second electrode which are electrically connected to the first mirror layer and are separated from each other; and a third electrode which is electrically connected to the second mirror layer, wherein the first mirror layer, the active layer, and the second mirror layer configure a laminated body, the laminated body includes a resonance portion which resonates light generated in the active layer, in a plan view, an insulation layer surrounding the laminated body is provided, and in the plan view, the insulation layer is provided between the first electrode and the second electrode.

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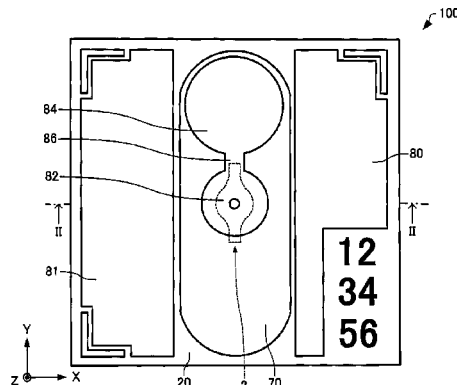
H01S 5/18311; H01S 5/1813; H01S 5/18322;

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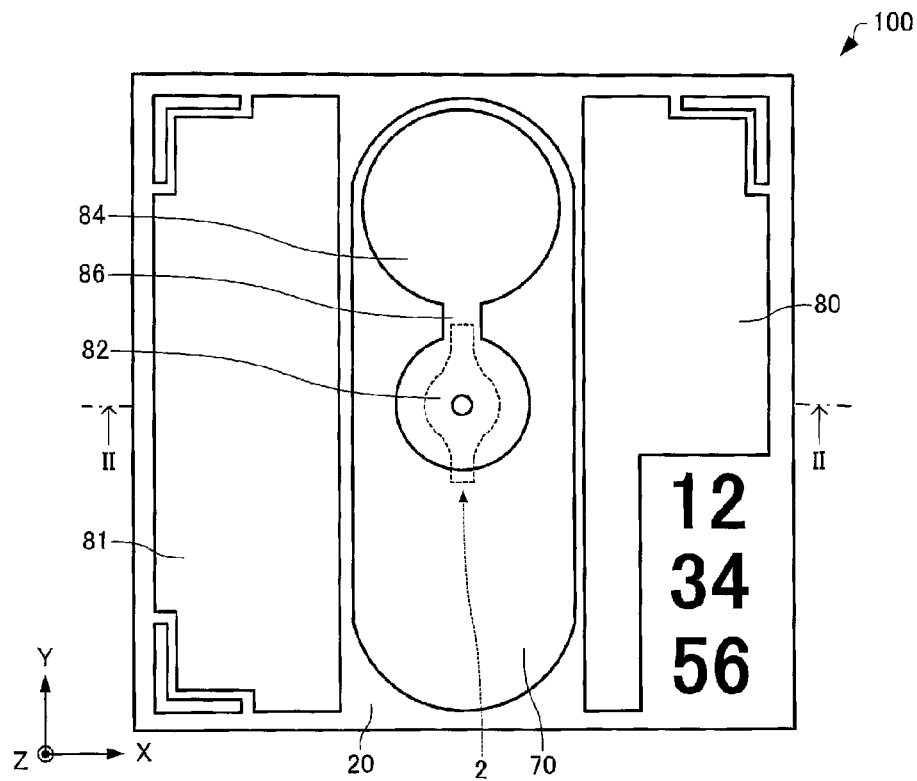


FIG. 1

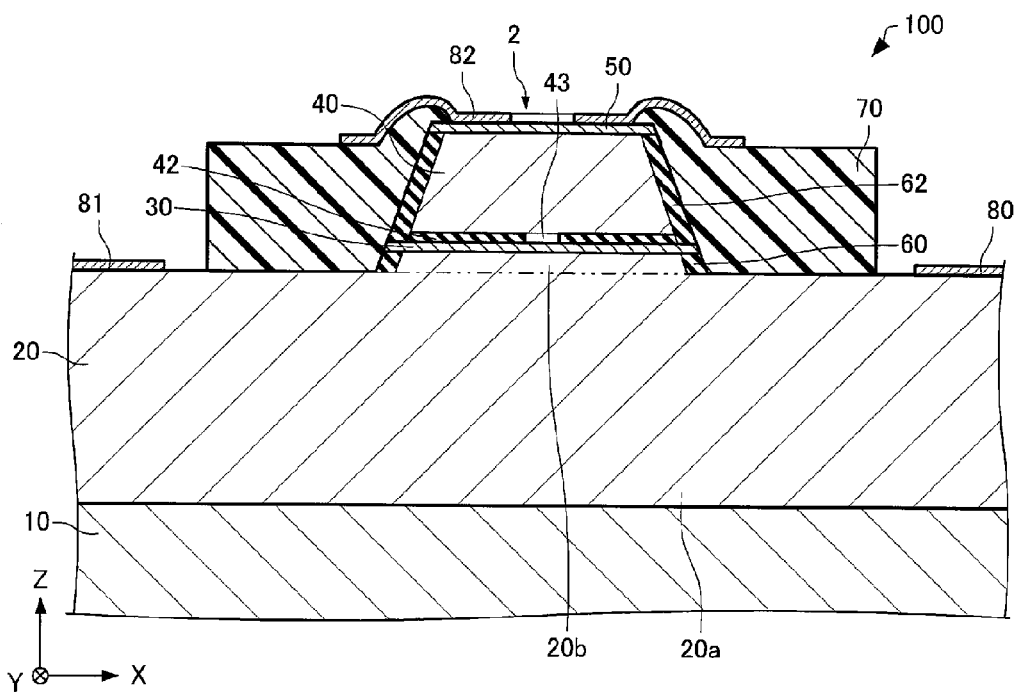


FIG. 2

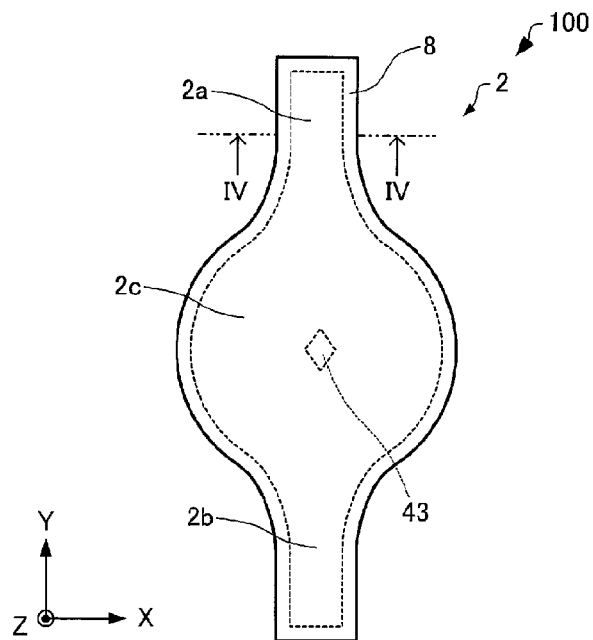


FIG. 3

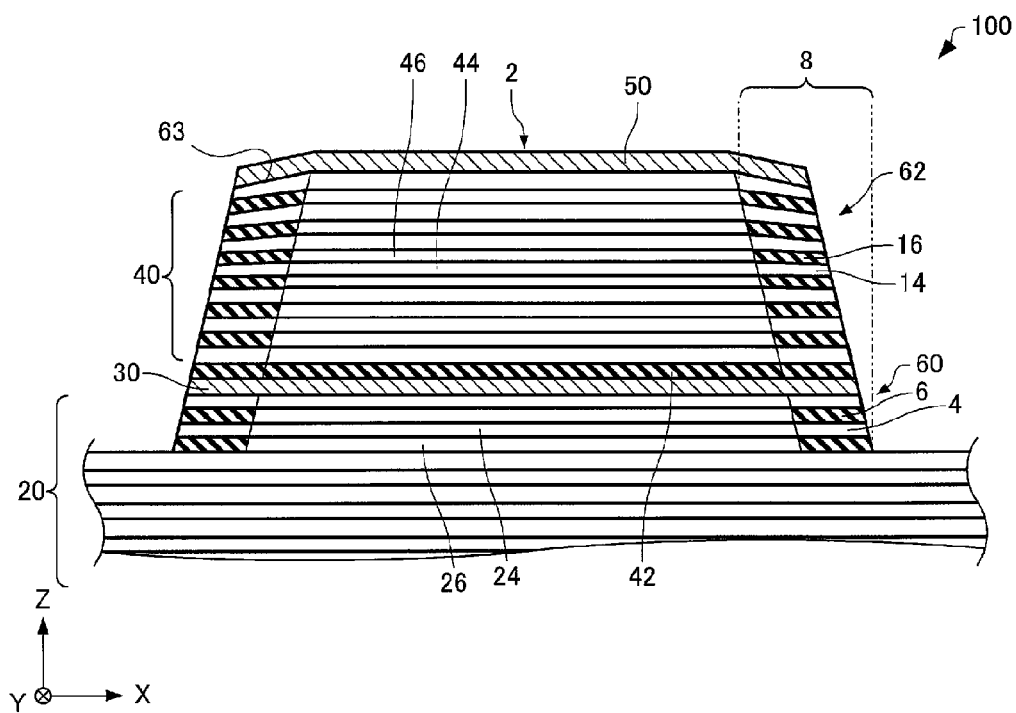


FIG. 4

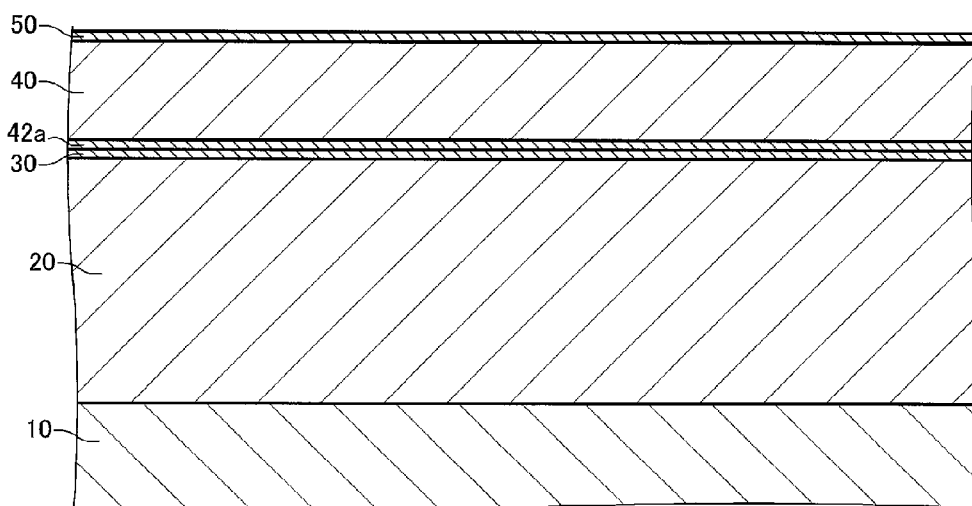


FIG. 5

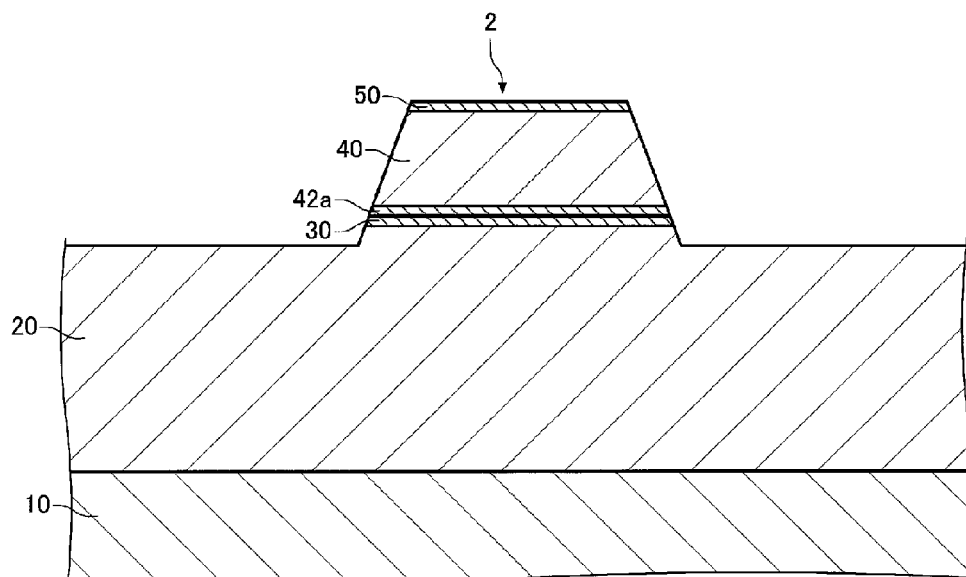


FIG. 6

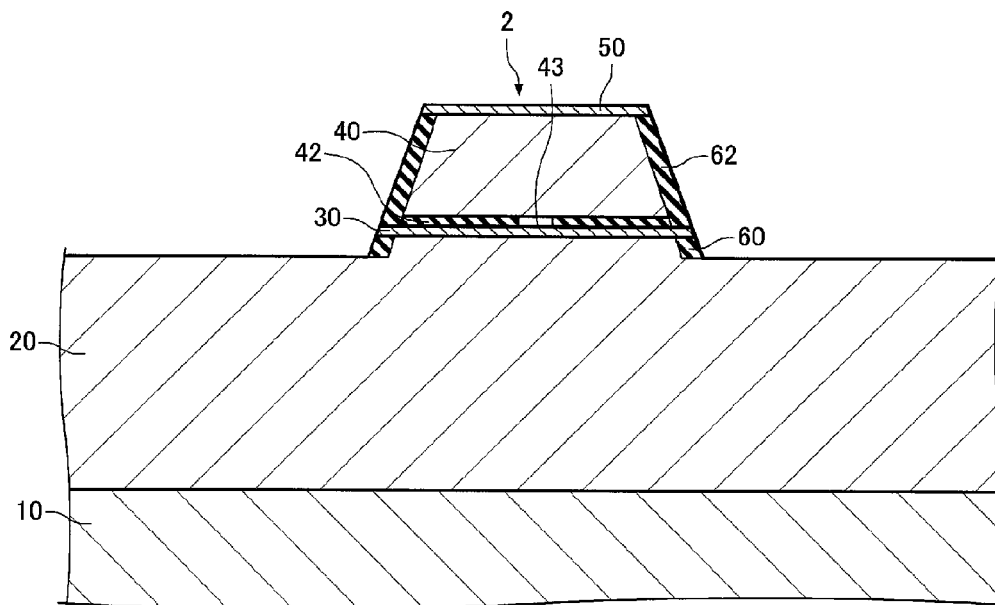


FIG. 7

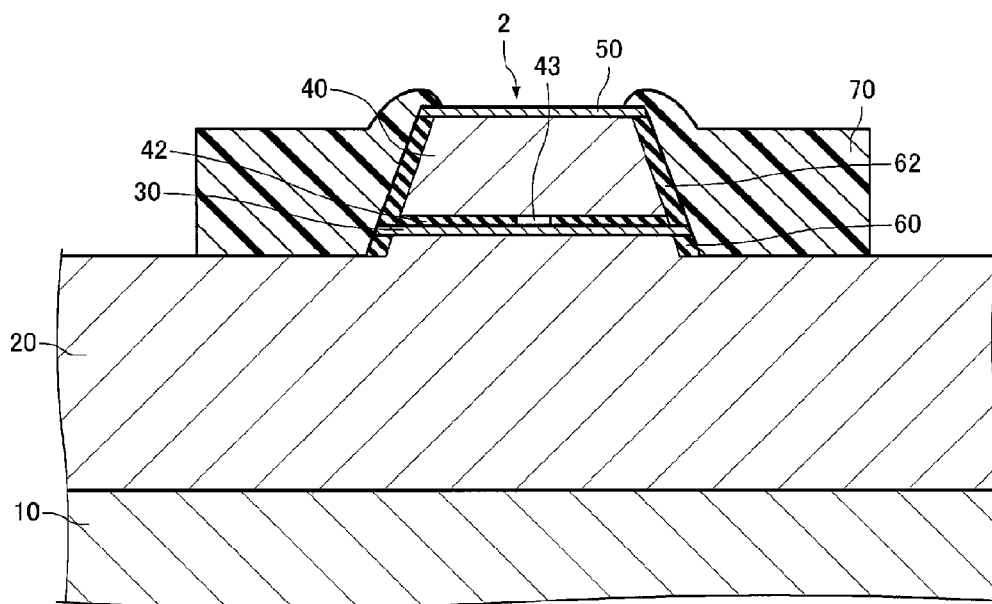


FIG. 8

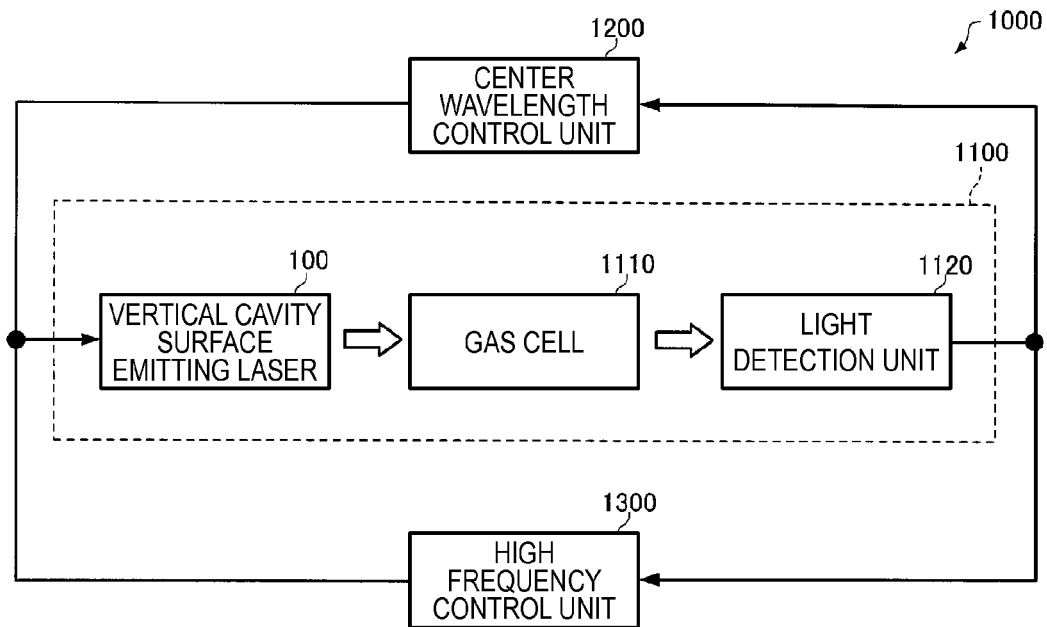


FIG. 9

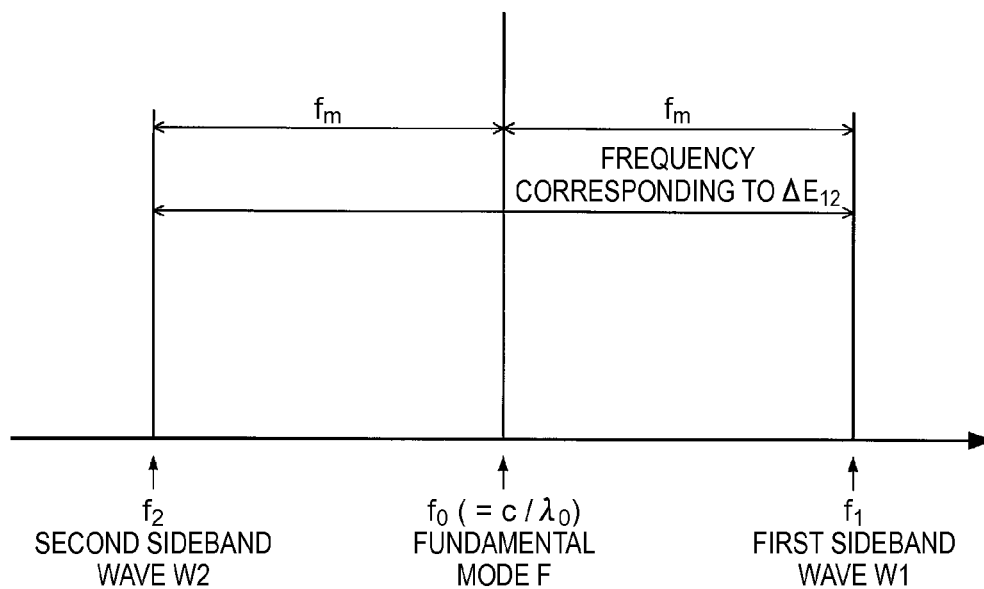


FIG.10

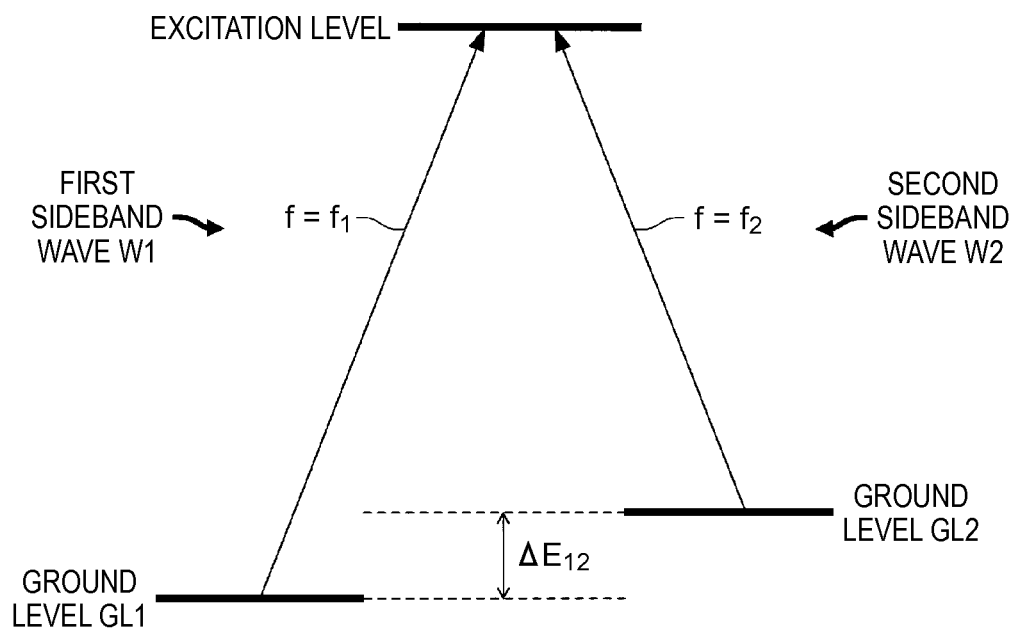


FIG.11

VERTICAL CAVITY SURFACE EMITTING LASER AND ATOMIC OSCILLATOR

BACKGROUND

1. Technical Field

The present invention relates to a vertical cavity surface emitting laser and an atomic oscillator.

2. Related Art

The vertical cavity surface emitting laser (VCSEL) is, for example, used as a light source of the atomic oscillator using coherent population trapping (CPT) which is one of the quantum interference effects.

JP-A-2007-165501, for example, discloses a vertical cavity surface emitting laser including: a columnar (vertical resonator) which is configured with a portion of a first mirror, an active layer, and a second mirror; an electrode which is provided on the first mirror; and an electrode which is provided on the second mirror.

However, in the vertical cavity surface emitting laser disclosed in JP-A-2007-165501, the electrode which is provided on the first mirror is only disposed on one side of the vertical resonator, and thus electric field distribution may be asymmetric with respect to the vertical resonator. When the electric field distribution is asymmetric with respect to the vertical resonator, intensity of laser light emitted from the vertical resonator, for example, may be asymmetric.

SUMMARY

An advantage of some aspects of the invention is to provide a vertical cavity surface emitting laser which can improve symmetry of electric field distribution with respect to a resonance portion. In addition, another advantage of some aspects of the invention is to provide an atomic oscillator including the vertical cavity surface emitting laser.

An aspect of the invention is directed to a vertical cavity surface emitting laser including: a substrate; a first mirror layer which is provided over the substrate; an active layer which is provided over the first mirror layer; a second mirror layer which is provided over the active layer; a first electrode and a second electrode which are electrically connected to the first mirror layer and are separated from each other; and a third electrode which is electrically connected to the second mirror layer, in which the first mirror layer, the active layer, and the second mirror layer configure a laminated body, the laminated body includes a resonance portion which resonates light generated in the active layer, in a plan view, an insulation layer surrounding the laminated body is provided, and in the plan view, the insulation layer is provided between the first electrode and the second electrode.

According to the vertical cavity surface emitting laser, since the insulation layer surrounding the laminated body is disposed between the first electrode and the second electrode, in a plan view, it is possible to improve symmetry of electric field distribution with respect to the resonance portion, for example, compared to a case where the electrode is only formed on one side of the insulation layer.

In the description according to the invention, for example, when a term "over" is used in a sentence such as "to form a specific element (hereinafter, referred to as a "B")) over another specific element (hereinafter, referred to as an "A"))", the term "over" is used to include a case of forming the B directly on the A and a case of forming the B on the A with another element interposed therebetween.

In the description according to the invention, for example, a phrase "electrical connection" is used with "a specific mem-

ber (hereinafter, referred to as a "B member") which is "electrically connected" to another specific member (hereinafter, referred to as an "A member"))". In the description according to the invention, in such an example, the phrase "electrical connection" is used to include a case where the A member and the B member directly come in contact with each other and are electrically connected, and a case where the A member and the B member are electrically connected with another member interposed therebetween.

In the vertical cavity surface emitting laser according to the aspect of the invention, in the plan view, the resonance portion may be provided between the first electrode and the second electrode.

According to the vertical cavity surface emitting laser, it is possible to improve the symmetry of the electric field distribution with respect to the resonance portion.

In the vertical cavity surface emitting laser according to the aspect of the invention, the first mirror layer may include a first portion which is provided over the substrate, and a second portion which is provided over the first portion and configures a portion of the laminated body, the first electrode and the second electrode may be provided on the first portion, and the third electrode may be provided on the laminated body.

According to the vertical cavity surface emitting laser, it is possible to improve the symmetry of the electric field distribution with respect to the resonance portion.

Another aspect of the invention is directed to an atomic oscillator including the vertical cavity surface emitting laser according to the aspect of the invention.

In such an atomic oscillator, it is possible to include a vertical cavity surface emitting laser which can improve the symmetry of the electric field distribution with respect to the resonance portion.

BRIEF DESCRIPTION OF THE DRAWINGS

The invention will be described with reference to the accompanying drawings, wherein like numbers reference like elements.

FIG. 1 is a plan view schematically showing a vertical cavity surface emitting laser according to the embodiment.

FIG. 2 is a cross-sectional view schematically showing a vertical cavity surface emitting laser according to the embodiment.

FIG. 3 is a plan view schematically showing a vertical cavity surface emitting laser according to the embodiment.

FIG. 4 is a cross-sectional view schematically showing a vertical cavity surface emitting laser according to the embodiment.

FIG. 5 is a cross-sectional view schematically showing a manufacturing step of a vertical cavity surface emitting laser according to the embodiment.

FIG. 6 is a cross-sectional view schematically showing a manufacturing step of a vertical cavity surface emitting laser according to the embodiment.

FIG. 7 is a cross-sectional view schematically showing a manufacturing step of a vertical cavity surface emitting laser according to the embodiment.

FIG. 8 is a cross-sectional view schematically showing a manufacturing step of a vertical cavity surface emitting laser according to the embodiment.

FIG. 9 is a functional block diagram of an atomic oscillator according to the embodiment.

FIG. 10 is a view showing frequency spectra of resonant light.

FIG. 11 is a view showing a relationship between Λ -shaped three level models of an alkaline metal atom, a first sideband wave, and a second sideband wave.

DESCRIPTION OF EXEMPLARY EMBODIMENTS

Hereinafter, preferred embodiments of the invention will be described in detail with reference to the drawings. The embodiments described below are not intended to unduly limit the contents of the invention disclosed in the aspects. All of the configurations described below are not limited to the essential constituent elements of the invention.

1. Vertical Cavity Surface Emitting Laser

First, a vertical cavity surface emitting laser according to the embodiment will be described with reference to the drawings. FIG. 1 is a plan view schematically showing a vertical cavity surface emitting laser 100 according to the embodiment. FIG. 2 is a cross-sectional view which is taken along line II-II of FIG. 1 and schematically shows the vertical cavity surface emitting laser 100 according to the embodiment. FIG. 3 is a plan view schematically showing the vertical cavity surface emitting laser 100 according to the embodiment. FIG. 4 is a cross-sectional view which is taken along line IV-IV of FIG. 3 and schematically shows the vertical cavity surface emitting laser 100 according to the embodiment.

For the sake of convenience, FIG. 2 shows a simplified laminated body 2. In FIG. 3, members other than the laminated body 2 of the vertical cavity surface emitting laser 100 are omitted. FIGS. 1 to 4 show an X axis, a Y axis, and a Z axis as three axes orthogonal to each other.

As shown in FIGS. 1 to 4, the vertical cavity surface emitting laser 100 includes a substrate 10, a first mirror layer 20, an active layer 30, a second mirror layer 40, a current constriction layer 42, a contact layer 50, first areas 60, second areas 62, a resin layer (insulation layer) 70, a first electrode 80, a second electrodes 81, and a third electrode 82.

The substrate 10 is, for example, a first conductive (for example, n-type) GaAs substrate.

The first mirror layer 20 is formed on the substrate 10. The first mirror layer 20 is a first conductive semiconductor layer. As shown in FIG. 4, the first mirror layer 20 is a distribution Bragg reflection (DBR) type mirror in which high refractive index layers 24 and low refractive index layers 26 are laminated onto each other. The high refractive index layer 24 is, for example, an n-type $\text{Al}_{0.12}\text{Ga}_{0.88}\text{As}$ layer on which silicon is doped. The low refractive index layer 26 is, for example, an n-type $\text{Al}_{0.9}\text{Ga}_{0.1}\text{As}$ layer on which silicon is doped. The number (number of pairs) of laminated high refractive index layers 24 and low refractive index layers 26 is, for example, 10 pairs to 50 pairs, specifically, 40.5 pairs.

The active layer 30 is provided on the first mirror layer 20. The active layer 30, for example, has a multiple quantum well (MQW) structure in which three layers having a quantum well structure configured with an i-type $\text{In}_{0.06}\text{Ga}_{0.94}\text{As}$ layer and an i-type $\text{Al}_{0.3}\text{Ga}_{0.7}\text{As}$ layer are overlapped.

The second mirror layer 40 is formed on the active layer 30. The second mirror layer 40 is a second conductive (for example, p-type) semiconductor layer. The second mirror layer 40 is a distribution Bragg reflection (DBR) type mirror in which high refractive index layers 44 and low refractive index layers 46 are laminated onto each other. The high refractive index layer 44 is, for example, a p-type $\text{Al}_{0.12}\text{Ga}_{0.88}\text{As}$ layer on which carbon is doped. The low refractive index layer 46 is, for example, a p-type $\text{Al}_{0.9}\text{Ga}_{0.1}\text{As}$ layer on which carbon is doped. The number (number of pairs) of laminated high refractive index layers 44

and low refractive index layers 46 is, for example, 3 pairs to 40 pairs, specifically, 20 pairs.

The second mirror layer 40, the active layer 30, and the first mirror layer 20 configure a vertical resonator-type pin diode. When a forward voltage of the pin diode is applied between the electrodes 80 and 81, and the electrode 82, recombination between electrons and positive holes occurs in the active layer 30, and the light emitting occurs. The light generated in the active layer 30 reciprocates between the first mirror layer 20 and the second mirror layer 40 (multiple reflection), the induced emission occurs at that time, and the intensity is amplified. When an optical gain exceeds an optical loss, laser oscillation occurs, and the laser light is emitted in a vertical direction (a lamination direction of the first mirror layer 20 and the active layer 30) from the upper surface of the contact layer 50.

The current constriction layer 42 is provided between the first mirror layer 20 and the second mirror layer 40. The current constriction layer 42 can also be provided in the first mirror layer 20 or the second mirror layer 40. In this case as well, the current constriction layer 42 is assumed to be provided between the first mirror layer 20 and the second mirror layer 40. In the example shown in the drawing, the current constriction layer 42 is provided on the active layer 30. The current constriction layer 42 is an insulation layer in which an opening 43 is formed. The current constriction layer 42 can prevent spreading of the current injected to a vertical resonator by the electrodes 80, 81, and in a planar direction (direction orthogonal to the lamination direction of the first mirror layer 20 and the active layer 30).

The contact layer 50 is provided on the second mirror layer 40. The contact layer 50 is a second conductive semiconductor layer. Specifically, the contact layer 50 is a p-type GaAs layer on which carbon is doped.

As shown in FIG. 4, the first areas 60 are provided on lateral portions of the first mirror layer 20 configuring the laminated body 2. The first areas 60 include a plurality of oxide layers 6 which are provided to be connected to the first mirror layer 20 (in the example shown in the drawing, a part of the first mirror layer 20). Specifically, first areas 60 are configured with the oxide layers 6 obtained by oxidizing layers connected to the low refractive index layers 26 (for example, $\text{Al}_{0.9}\text{Ga}_{0.1}\text{As}$ layers) configuring the first mirror layer 20, and layers 4 connected to the high refractive index layers 24 (for example, $\text{Al}_{0.12}\text{Ga}_{0.88}\text{As}$ layers) configuring the first mirror layer 20 which are laminated on each other.

The second areas 62 are provided on lateral portions of the second mirror layer 40 configuring the laminated body 2. The second areas 62 include a plurality of oxide layers 16 which are provided to be connected to the second mirror layer 40. Specifically, the second areas 62 are configured with the oxide layers 16 obtained by oxidizing layers connected to the low refractive index layers 46 (for example, $\text{Al}_{0.9}\text{Ga}_{0.1}\text{As}$ layers) configuring the second mirror layer 40, and layers 14 connected to the high refractive index layers 44 (for example, $\text{Al}_{0.12}\text{Ga}_{0.88}\text{As}$ layers) configuring the second mirror layer 40 which are laminated on each other. In a plan view (when seen from the lamination direction of the first mirror layer 20 and the active layer 30), oxide areas 8 are configured by the first areas 60 and the second areas 62.

The first mirror layer 20, the active layer 30, the second mirror layer 40, the current constriction layer 42, the contact layer 50, the first areas 60, and the second areas 62 configure the laminated body 2. In the example shown in FIGS. 1 and 2, the laminated body 2 is surrounded with the resin layer 70.

In the example shown in FIG. 3, in a plan view, a length of the laminated body 2 in a Y axis direction is greater than a

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length of the laminated body **2** in an X axis direction. That is, a longitudinal direction of the laminated body **2** is the Y axis direction. In a plan view, the laminated body **2** is, for example, symmetrical about a virtual straight line which passes through the center of the laminated body **2** and is parallel to the X axis. In a plan view, the laminated body **2** is, for example, symmetrical about a virtual straight line which passes through the center of the laminated body **2** and is parallel to the Y axis.

In a plan view as shown in FIG. 3, the laminated body **2** includes a first distortion imparting portion (first portion) **2a**, a second distortion imparting portion (second portion) **2b**, and a resonance portion (third portion) **2c**.

In a plan view, the first distortion imparting portion **2a** and the second distortion imparting portion **2b** face each other in the Y axis direction with the resonance portion **2c** interposed therebetween. In a plan view, the first distortion imparting portion **2a** is protruded from the resonance portion **2c** in the positive Y axis direction. In a plan view, the second distortion imparting portion **2b** is protruded from the resonance portion **2c** in the negative Y axis direction. The first distortion imparting portion **2a** and the second distortion imparting portion **2b** are provided to be integrated with the resonance portion **2c**.

The first distortion imparting portion **2a** and the second distortion imparting portion **2b** impart distortion to the active layer **30** and polarize light generated in the active layer **30**. Herein, to polarize the light is to set a vibration direction of an electric field of the light to be constant. The semiconductor layers (the first mirror layer **20**, the active layer **30**, the second mirror layer **40**, the current constriction layer **42**, the contact layer **50**, the first areas **60**, and the second areas **62**) configuring the first distortion imparting portion **2a** and the second distortion imparting portion **2b** are a generation source which generates distortion to be imparted to the active layer **30**. Since the first distortion imparting portion **2a** and the second distortion imparting portion **2b** include the first areas **60** including the plurality of oxide layers **6** and the second areas **62** including the plurality of oxide layers **16**, it is possible to impart a large amount of distortion to the active layer **30**.

The resonance portion **2c** is provided between the first distortion imparting portion **2a** and the second distortion imparting portion **2b**. A length of the resonance portion **2c** in the X axis direction is greater than a length of the first distortion imparting portion **2a** in the X axis direction or a length of the second distortion imparting portion **2b** in the X axis direction. A planar shape of the resonance portion **2c** (shape when seen from the lamination direction of the first mirror layer **20** and the active layer **30**) is, for example, a circle.

The resonance portion **2c** resonates light generated in the active layer **30**. That is, the vertical resonator is formed in the resonance portion **2c**.

The resin layer **70** is provided at least on side surfaces of the laminated body **2**. In the example shown in FIG. 1, the resin layer **70** covers the first distortion imparting portion **2a** and the second distortion imparting portion **2b**.

That is, the resin layer **70** is provided on the side surface of the first distortion imparting portion **2a**, the upper surface of the first distortion imparting portion **2a**, the side surface of the second distortion imparting portion **2b**, and the upper surface of the second distortion imparting portion **2b**. The resin layer **70** may completely cover the first distortion imparting portion **2a** and the second distortion imparting portion **2b**, or may cover some of the first distortion imparting portion **2a** and the second distortion imparting portion **2b**. The material of the resin layer **70** is, for example, polyimide. In the embodiment, the resin layer **70** for applying the distortion to the distortion imparting portions **2a** and **2b** is used, but since a configuration

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corresponding to the resin layer **70** is only necessary to have a function of insulating, the resin may not be used, as long as it is an insulation material.

In the example shown in FIG. 3, in a plan view, a length of the resin layer **70** in the Y axis direction is greater than a length of the resin layer **70** in the X axis direction. That is, a longitudinal direction of the resin layer **70** is the Y axis direction. The longitudinal direction of the resin layer **70** and the longitudinal direction of the laminated body **2** coincide with each other.

The first electrode **80** and the second electrode **81** are provided on the first mirror layer **20**. The first electrode **80** and the second electrode **81** form ohmic contact with the first mirror layer **20**. The first electrode **80** and the second electrode **81** are electrically connected to the first mirror layer **20**. As the first electrode **80** and the second electrode **81**, an electrode in which a Cr layer, an AuGe layer, an Ni layer, and an Au layer are laminated in this order from the first mirror layer **20** side is used, for example. The first electrode **80** and the second electrode **81** are the electrodes for injecting the current to the active layer **30**.

The third electrodes **82** are provided on the contact layer **50** (on the laminated body **2**). The third electrodes **82** form ohmic contact with the contact layer **50**. In the example shown in the drawing, the third electrodes **82** are also formed on the resin layer **70**. The third electrodes **82** are electrically connected to the second mirror layer **40** through the contact layer **50**. As the third electrodes **82**, an electrode in which a Cr layer, a Pt layer, a Ti layer, a Pt layer, and an Au layer are laminated in this order from the contact layer **50** side is used, for example. The third electrodes **82** are the other electrodes for injecting the current to the active layer **30**.

The third electrodes **82** are electrically connected to a pad **84**. In the example shown in the drawing, the third electrodes **82** are electrically connected to the pad **84** through a lead-out wiring **86**. The pad **84** is provided on the resin layer **70**. The material of the pad **84** and the lead-out wiring **86** is, for example, the same as the material of the third electrodes **82**.

Herein, the first electrode **80** and the second electrode **81** will be described in detail.

The first electrode **80** and the second electrode **81** are provided to be separated from each other. That is, the first electrode **80** and the second electrode **81** are provided to be separated with a gap therebetween. In a plan view, the resin layer **70** is provided between the first electrode **80** and the second electrode **81**. In the example shown in the drawing, the first electrode **80** is provided on one side (positive X axis direction side) of the resin layer **70** in a plan view, and the second electrode **81** is provided on the other side (negative X axis direction side) of the resin layer **70** in a plan view. As described above, in the vertical cavity surface emitting laser **100**, electrodes electrically connected to the first mirror layer **20** are divided into the first electrode **80** and the second electrode **81** and are provided on both sides of the resin layer **70**, respectively.

In a plan view, a length (for example, the greatest length) of the first electrode **80** in the Y axis direction is greater than a length (for example, the greatest length) of the first electrode **80** in the X axis direction. That is, the first electrode **80** has a shape having a longitudinal direction in the Y axis direction. In addition, in a plan view, a length (for example, the greatest length) of the second electrode **81** in the Y axis direction is greater than a length (for example, the greatest length) of the second electrode **81** in the X axis direction. That is, the second electrode **81** has a shape having a longitudinal direction in the Y axis direction. The longitudinal direction of the first electrode **80** and the longitudinal direction of the second electrode

81 are the same direction as the longitudinal direction of the resin layer **70**. The greatest length of the first electrode **80** in the Y axis direction is equivalent to the greatest length of the second electrode **81** in the Y axis direction.

In a plan view, the resin layer **70** is provided so as to surround the resonance portion **2c**. In a plan view, the resonance portion **2c** is provided between the first electrode **80** and the second electrode **81**. For example, in a plan view, a distance (shortest distance) between the resonance portion **2c** and the first electrode **80** is equivalent to a distance (shortest distance) between the resonance portion **2c** and the second electrode **81**.

As shown in FIG. 2, the first mirror layer **20** includes a first portion **20a** which is provided on the substrate **10**, and a second portion **20b** which is provided on the first portion **20a** and configures a part of the laminated body **2**. The first electrode **80** and the second electrode **81** are provided on the first portion **20a** of the first mirror layer **20**. As described above, the third electrode **82** is provided on the laminated body **2**. As described above, the electrodes **80**, **81**, and **82** are provided on the upper surface side (positive Z axis direction side) of the substrate **10**.

In the above description, the AlGaAs vertical cavity surface emitting laser has been described, but GaInP, ZnSSe, InGaN, AlGaIn, InGaAs, GaInNAs, or GaAsSb semiconductor materials may be used according to the oscillation wavelength, for the vertical cavity surface emitting laser according to the invention.

The vertical cavity surface emitting laser **100**, for example, has the following characteristics.

In the vertical cavity surface emitting laser **100**, in a plan view, the resin layer **70** is provided so as to surround the laminated body **2** and the resin layer **70** is provided between the first electrode **80** and the second electrode **81**. Accordingly, it is possible to improve symmetry of electric field distribution with respect to the resonance portion **2c**, for example, compared to a case where the electrode is only formed on one side of the resin layer **70** (compared to a case where the first electrode **80** is only provided, for example). In the vertical cavity surface emitting laser **100**, since the first electrode **80** and the second electrode **81** are separated from each other, the connected portion of the first electrode **80** and the second electrode **81** is not necessary and it is possible to realize miniaturization, for example, compared to a case where the first electrode **80** and the second electrode **81** are connected to each other.

In the vertical cavity surface emitting laser **100**, in a plan view, the resonance portion **2c** is provided between the first electrode **80** and the second electrode **81**. Accordingly, it is possible to improve the symmetry of the electric field distribution with respect to the resonance portion **2c**, for example, compared to a case where the electrode is only formed on one side of the resin layer **70**.

In the vertical cavity surface emitting laser **100**, the first electrode **80** and the second electrode **81** are provided on the first portion **20a** of the first mirror layer **20** and the third electrode **82** is provided on the laminated body **2**. Accordingly, it is possible to obtain a one-sided electrode structure, for example.

2. Manufacturing Method of Vertical Cavity Surface Emitting Laser

Next, a manufacturing method of the vertical cavity surface emitting laser according to the embodiment will be described with reference to the drawings. FIGS. 5 to 8 are cross-sectional views schematically showing manufacturing steps of the vertical cavity surface emitting laser **100** according to the embodiment, and correspond to FIG. 2.

As shown in FIG. 5, the first mirror layer **20**, the active layer **30**, the layer to be oxidized **42a** which is to be the oxidized current constriction layer **42**, the second mirror layer **40**, and the contact layer **50** are epitaxially grown in this order, on the substrate **10**. As an epitaxial growth method, a metal organic chemical vapor deposition (MOCVD) method or a molecular beam epitaxy (MBE) method is used, for example.

As shown in FIG. 6, the contact layer **50**, the second mirror layer **40**, the layer to be oxidized **42a**, the active layer **30**, and first mirror layer **20** are patterned to form the laminated body **2**. The patterning is performed by photolithography or etching, for example.

As shown in FIG. 7, the layer to be oxidized **42a** is oxidized to form the current constriction layer **42**. The layer to be oxidized **42a** is, for example, an $\text{Al}_x\text{Ga}_{1-x}\text{As}$ ($x \geq 0.95$) layer. The substrate **10** on which the laminated body **2** is formed is put in a steam atmosphere at approximately 400° C., to oxidize the $\text{Al}_x\text{Ga}_{1-x}\text{As}$ ($x \geq 0.95$) layer from the lateral side, and accordingly the current constriction layer **42** is formed.

In the manufacturing method of the vertical cavity surface emitting laser **100**, in the oxidation step, a layer configuring the first mirror layer **20** is oxidized from the lateral side to form the first area **60**. A layer configuring the second mirror layer **40** is oxidized from the lateral side to form the second area **62**. Specifically, due to the steam atmosphere at approximately 400° C., arsenic in the $\text{Al}_{0.9}\text{Ga}_{0.1}\text{As}$ layer configuring the mirror layers **20** and **40** is substituted with oxygen, and the areas **60** and **62** are formed. The areas **60** and **62**, for example, contract when returning the temperature from the high temperature of approximately 400° C. to the room temperature, and the upper surface **63** of the second area **62** is inclined to the substrate **10** side (see FIG. 4). The first distortion imparting portion **2a** and the second distortion imparting portion **2b** can apply distortion (stress) caused by the contraction of the areas **60** and **62** to the active layer **30**.

As shown in FIG. 8, the resin layer **70** is formed so as to surround the laminated body **2**. The resin layer **70** is formed, for example, by forming a layer formed of a polyimide resin on the upper surface of the first mirror layer **20** and the entire surface of the laminated body **2** using a spin coating method and patterning the layer. The patterning is performed by photolithography or etching, for example. Next, the resin layer **70** is hardened by performing a heating process (curing). The resin layer **70** contracts due to the heating process. In addition, the resin layer **70** contracts when returning the temperature in the heating step to a room temperature.

As shown in FIG. 2, the third electrode **82** is formed on the contact layer **50** and the resin layer **70**, and the first electrode **80** and the second electrode **81** are formed on the first mirror layer **20**. In a plan view, the first electrode **80** is formed on one side of the resin layer **70** and the second electrode **81** is formed on the other side of the resin layer **70**, in a plan view. The electrodes **80**, **81**, and **82** are, for example, formed by a combination of a vacuum vapor deposition method and a lift-off method. The order of forming the electrodes **80**, **81** and **82** is not particularly limited. In the step of forming the third electrode **82**, the pad **84** and the lead-out wiring **86** (see FIG. 1) may be formed. A chip number provided in a chip number writing area **90** may be formed in a step of forming the electrodes **80** and **81**, or may be formed in a step of forming the third electrode **82**.

It is possible to manufacture the vertical cavity surface emitting laser **100** with the steps described above.

3. Atomic Oscillator

Next, an atomic oscillator according to the embodiment will be described with reference to the drawings. FIG. 9 is a functional block diagram of an atomic oscillator 1000 according to the embodiment.

As shown in FIG. 9, the atomic oscillator 1000 is configured to include an optical module 1100, a center wavelength control unit 1200, and a high frequency control unit 1300.

The optical module 1100 includes the vertical cavity surface emitting laser according to the invention (in the example shown in the drawing, the vertical cavity surface emitting laser 100), a gas cell 1110, and a light detection unit 1120.

FIG. 10 is a view showing frequency spectra of light emitted by the vertical cavity surface emitting laser 100. FIG. 11 is a view showing a relationship between Λ -shaped three level models of an alkaline metal atom, a first sideband wave W1, and a second sideband wave W2. The light emitted from the vertical cavity surface emitting laser 100 includes a fundamental mode F including a center frequency f_0 ($=c/\lambda_0$; c represents velocity of light and λ_0 represents a center wavelength of laser light), the first sideband wave W1 including a frequency f_1 in an upstream sideband with respect to the center frequency f_0 , and the second sideband wave W2 including a frequency f_2 in a downstream sideband with respect to the center frequency f_0 , shown in FIG. 10. The frequency f_1 of the first sideband wave W1 satisfies $f_1=f_0+f_m$, and the frequency f_2 of the second sideband wave W2 satisfies $f_2=f_0-f_m$.

As shown in FIG. 11, a difference in frequencies between the frequency f_1 of the first sideband wave W1 and the frequency f_2 of the second sideband wave W2 coincides with a frequency corresponding to a difference in energy ΔE_{12} between a ground level GL1 and a ground level GL2 of the alkaline metal atom. Accordingly, the alkaline metal atom causes an EIT phenomenon to occur due to the first sideband wave W1 including the frequency f_1 and the second sideband wave W2 including the frequency f_2 .

In the gas cell 1110, a gaseous alkaline metal atom (sodium atom, rubidium atom, cesium atom, and the like) is sealed in a container. When two light waves including the frequency (wavelength) corresponding to the difference in energy between two ground levels of the alkaline metal atom are emitted to the gas cell 1110, the alkaline metal atom causes the EIT phenomenon to occur. For example, if the alkaline metal atom is a sodium atom, the frequency corresponding to the difference in energy between the ground level GL1 and the ground level GL2 in a D1 line is 9.19263 . . . GHz. Accordingly, when two light waves including the difference in frequency of 9.19263 . . . GHz are emitted, the EIT phenomenon occurs.

The light detection unit 1120 detects the intensity of the light penetrating the alkaline metal atom sealed in the gas cell 1110. The light detection unit 1120 outputs a detection signal according to the amount of the light penetrating the alkaline metal atom. As the light detection unit 1120, a photodiode is used, for example.

The center wavelength control unit 1200 generates driving current having a magnitude corresponding to the detection signal output by the light detection unit 1120, supplies the driving current to the vertical cavity surface emitting laser 100, and controls the center wavelength λ_0 of the light emitted by the vertical cavity surface emitting laser 100. The center wavelength λ_0 of the laser light emitted by the vertical cavity surface emitting laser 100 is minutely adjusted and stabilized, by a feedback loop passing through the vertical cavity surface emitting laser 100, the gas cell 1110, the light detection unit 1120, and the center wavelength control unit 1200.

The high frequency control unit 1300 controls so that the difference in wavelengths (frequencies) between the first sideband wave W1 and the second sideband wave W2 is equivalent to the frequency corresponding to the difference in energy between two ground levels of the alkaline metal atom sealed in the gas cell 1110, based on the detection result output by the light detection unit 1120. The high frequency control unit 1300 generates a modulation signal including a modulation frequency f_m (see FIG. 10) according to the detection result output by the light detection unit 1120.

Feedback control is performed so that the difference in frequencies between the first sideband wave W1 and the second sideband wave W2 is extremely accurately equivalent to the frequency corresponding to the difference in energy between two ground levels of the alkaline metal atom, by a feedback loop passing through the vertical cavity surface emitting laser 100, the gas cell 1110, the light detection unit 1120, and the high frequency control unit 1300. As a result, the modulation frequency f_m becomes an extremely stabilized frequency, and therefore, the modulation signal can be set as an output signal (clock output) of the atomic oscillator 1000.

Next, the operations of the atomic oscillator 1000 will be described with reference to FIGS. 9 to 11.

The laser light emitted from the vertical cavity surface emitting laser 100 is incident to the gas cell 1110. The light emitted from the vertical cavity surface emitting laser 100 includes two light waves (the first sideband wave W1 and the second sideband wave W2) including the frequency (wavelength) corresponding to the difference in energy between two ground levels of the alkaline metal atom, and the alkaline metal atom causes the EIT phenomenon to occur. The intensity of the light penetrating the gas cell 1110 is detected by the light detection unit 1120.

The center wavelength control unit 1200 and the high frequency control unit 1300 perform the feedback control so that the difference in frequencies between the first sideband wave W1 and the second sideband wave W2 extremely accurately coincides with the frequency corresponding to the difference in energy between two ground levels of the alkaline metal atom. In the atomic oscillator 1000, a rapid change in a light absorbing behavior when the difference in frequencies f_1 - f_2 between the first sideband wave W1 and the second sideband wave W2 is deviated from the frequency corresponding to the difference in energy ΔE_{12} between the ground level GL1 and the ground level GL2, is detected and controlled using the EIT phenomenon, and therefore it is possible to obtain an oscillator with high accuracy.

The invention has configurations substantially same as the configurations described in the embodiments (for example, configurations with the same function, method, and effects, or configurations with the same object and effect). The invention includes a configuration in which non-essential parts of the configurations described in the embodiments are replaced. The invention includes a configuration having the same operation effect as the configurations described in the embodiments or a configuration which can achieve the same object. The invention includes a configuration obtained by adding a well-known technology to the configurations described in the embodiments.

The entire disclosure of Japanese Patent Application No. 2013-263467, filed Dec. 20, 2013 is expressly incorporated by reference herein.

What is claimed is:

1. A vertical cavity surface emitting laser comprising:
 - a substrate;
 - a first mirror layer which is provided over the substrate;
 - an active layer which is provided over the first mirror layer;

a second mirror layer which is provided over the active layer;
 a first electrode and a second electrode which are electrically connected to the first mirror layer and are separated from each other; and
 a third electrode which is electrically connected to the second mirror layer,
 wherein the first mirror layer, the active layer, and the second mirror layer configure a laminated body,
 the laminated body includes a resonance portion which resonates light generated in the active layer,
 in a plan view, an insulation layer surrounding the laminated body is provided, and
 in the plan view, the insulation layer is provided between the first electrode and the second electrode,
 the first mirror layer includes a first portion which is provided over the substrate, and a second portion which is provided over the first portion and configures a portion of the laminated body,
 the first electrode and the second electrode are provided on the first portion, and
 the third electrode is provided on the laminated body.

2. The vertical cavity surface emitting laser according to claim 1,
 wherein, in the plan view, the resonance portion is provided between the first electrode and the second electrode.

3. An atomic oscillator comprising:
 the vertical cavity surface emitting laser according to claim 1.

4. An atomic oscillator comprising:
 the vertical cavity surface emitting laser according to claim 2.

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